Sheet. 1- of: 3

Form PTO-1449 U.S. DEPARTMENT OF COMMERCE (REV. 8-83) PATENT AND TRADEMARK OFFICE					NO.	SERIAL NO. Not Yet Assigned			
INFOR	MATIO	N DISCLOSURE	CITATION	NREL 01-43					
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			U. S.	PATENT DOCUM	MENTS				
Examiner INITIAL	REF	DOCUMENT NUMBER	DATE	NAME				G DATE ROPRIATE	
10.444	_	4,612,411	09/16/86	^¹ Wieting	136	265			
		5,078,803	01/17/92	Pier et al.	136	256			
		5,324,365	06/28/94	Niwa	136	256			
	*	5,420,043	05/30/95	Niwa	438	96			
		5,458,753	10/17/95	Sato et al.	204	192.29			
		5,578,501	11/26/96	Niwa	438	96			
		5,604,133	02/18/97	Aoike	438	96			
		5,612,229	03/18/97	Yoshida	438	72			
		5,620,924	04/15/97	Takizawa	427	108			
		-	FOREIGN PAT	ENT DOCUMENT	S				
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANS	SLATION	
							YES	NO	

•	OTHER DOCUMENTS (Including	g Author, Title, Date, Pertinent Pages, Etc.)
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*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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Sheet 2 of 3

Form PTO-1449 U.S. DEPARTMENT OF COMMERCE (REV. 8-83) PATENT AND TRADEMARK OFFICE			E	SERIAL NO. Not Yet Assigned				
INFOR	RMATIO	N DISCLOSURE	NREL 01-43	NREL 01-43				
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				FILING DATE		GROUP Not Yet Assigned		
			U. S	S. PATENT DOCUM	MENTS			
Examiner INITIAL	REF	DOCUMENT NUMBER	DATE	NAME				G DATE ROPRIATE
		5,716,480	02/10/98	Matsuyama et al.	136	249		
		5,804,466	09/08/98	Arao et al.	438	95		
·		5,913,986	06/22/99	Matsuyama	136	255		
		5,990,416	11/23/99	Windisch et al.	136	255		
		6,040,521	03/21/00	Kushiya et al.	136	265		
		6,043,427	03/28/00	. Nishimoto	136	258		
		6,107,116	08/22/00	Kariya et al.	438	87		
		6,187,150 B1	02/13/01	Yoshimi et al.	204	192.29		
		6,238,808	05/29/01	Arao et al.	428	629		
		6,424,687B1	06/15/01	Schropp	136	255		
			FOREIGN PAT	TENT DOCUMENTS	S .			
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		OTHER DOCUME	ENTS (Including A	uthor, Title, Date, F	Pertinent Page	əs, Etc.)		
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		5,756,207	05/26/1998	Clough et al.					
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)					
	AA	M. Joseph et al., "p-type Electrical Conduction in ZnO Thin films by Ga and N Codoping," Jpn. J. Appl. Phys. 38, (1999) pp. L1205-1207			
	AB	K. Minegishi et al., "Growth of p-type Zinc oxide Films by Chemical Vapor Deposition, "Jpn. J. Appl. Phys. 36, (1997) pp. L1453-L145			
	AC	X. Gao et al., "Pulsed Reactive Laser Deposition of p-type ZnO Film Enhanced by an Electron Cyclotron Resonance Source., "J. of Crystal Growth, 223 (2001) 135-139			
	AD	S. B. Zhang et al. J. Appl. Phys. 83, 3192 (1998).			
	AE	Y. Sato et al., Thin Solid Films 281-282, 445 (1996)			
	AF	Yan et al. in "Control of Doping by impurity Chemical Potentials: Predictions for p-Type ZnO, "Physical Review Letters 86, 5723 (2001)			